



State-of-Art in Optical Tweezers

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Message from the Guest Editors

Dear Colleagues,

Optical tweezers (OTs) enable trapping and manipulation without contact and apply minute forces on microscopic particles. Since the pioneering work of Arthur Ashkin, OTs have been developed at a dazzling speed.

To maintain the pace in recent advancements regarding OTs, the Special Issue, entitled “State of the Art in Optical Tweezers”, welcomes contributions regarding all aspects of optical trapping and manipulation. Theoretical and experimental studies are welcome, as well as articles concerning applications of OT in all the fields of science. This Special Issue will accept all forms of contributions, including research papers, communications and review articles.

Dr. Ruben Ramos-Garcia
Prof. Dr. Gabriel Spalding
Guest Editors





Editor-in-Chief

Message from the Editor-in-Chief

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